

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Currently amended) A laminated piezoelectric element ~~having a thickness of 100µm or less, comprising:~~  
a laminate ~~which comprises~~ having a plurality of piezoelectric ceramic layers; and  
electrodes provided at least ~~one of the~~ on a surface and ~~the inside of said the~~ laminate, wherein ~~said the~~ electrodes ~~comprises~~ include a silver-palladium alloy containing 71 to 99.9% by volume of silver and 0.1 to 29% by volume of palladium and the laminated piezoelectric element has a thickness of 100µm or less.
2. (Currently amended) The laminated piezoelectric element according to claim 1, wherein ~~said the~~ electrodes ~~comprises~~ include a silver-palladium alloy containing 87% by volume or more silver, and a residual stress remaining inside is 100MPa or less.
3. (Currently amended) The laminated piezoelectric element according to claim 1, wherein ~~said the~~ piezoelectric ceramic layers contains Pb.
4. (Currently amended) The laminated piezoelectric element according to claim 1, wherein ~~said the~~ electrodes contains a piezoelectric ceramic material, and ~~the~~ proportions of the silver-palladium alloy to the piezoelectric ceramic material are in a range from 100: 16 to 60.

5. (Currently amended) The laminated piezoelectric element according to claim 4, wherein ~~said~~ the piezoelectric ceramic material has a mean crystal grain size of 0.9 $\mu$ m or less.

6. (Original) The laminated piezoelectric element according to claim 1, wherein each piezoelectric ceramic layer is in a range from 1 to 25 $\mu$ m in thickness.

7. (Currently amended) The laminated piezoelectric element according to claim 1, wherein variations in a d constant is within  $\pm 10\%$  across the surface when a voltage is applied between the electrodes.

8. (Currently amended) The laminated piezoelectric element according to claim 1, wherein a bonding strength between ~~said~~ the electrodes and ~~said~~ the piezoelectric ceramic layer is 1.25MPa or higher.

9. (Original) An actuator comprising the laminated piezoelectric element of claim 1.

10. (Currently amended) The actuator according to claim 9, wherein a supporting member is bonded onto ~~the~~ a bottom surface of ~~said~~ the laminated piezoelectric element.

11. (Currently amended) An actuator, comprising:  
an oscillator plate;  
internal electrodes provided on ~~said~~ the oscillator plate;  
a piezoelectric ceramic layer provided on ~~said~~ the internal electrodes;  
and  
a plurality of surface electrodes provided on ~~said~~ the piezoelectric ceramic layer,

wherein ~~said~~ the oscillator plate, ~~said~~ the internal electrodes, ~~said~~ the piezoelectric ceramic layer and ~~said~~ the surface electrodes ~~comprise~~ include the laminated piezoelectric element of claim 1.

12. (Currently amended) A printing head comprising a flow passage member in which a plurality of ink compressing chambers having ink nozzles are arranged and the actuator of claim 11 mounted on the flow passage member, wherein the ink compressing chambers and ~~said~~ the surface electrodes ~~is~~ are aligned with each other.

13. (New) A method of manufacturing a laminated piezoelectric element, comprising:  
forming a laminated having a plurality of piezoelectric ceramic layers;  
providing electrodes at least on a surface and inside the laminate with the electrodes having a silver-palladium alloy containing 71 to 99 % by volume of silver and 0.1 to 29% by volume of palladium; and  
forming the laminated piezoelectric element with a thickness of 100µm or less.

14. (New) The method of manufacturing according to claim 13, further comprising providing the electrodes with a silver-palladium alloy containing 87% by volume or more silver and obtaining a remaining residual stress inside of 100 MPa or less.

15. (New) The method of manufacturing according to claim 13, further comprising forming the piezoelectric ceramic layers with 9b.

16. (New) The method of manufacturing according to claim 13, further comprising forming the electrodes with a piezoelectric material and the proportions

of the silver-palladium alloy to the piezoelectric ceramic material are in a range from 100:16 to 60.

17. (New) The method of manufacturing according to claim 16, further comprising providing the piezoelectric ceramic material with a mean crystal grain size of 0.9 $\mu$ m or less.

18. (New) The method of manufacturing according to claim 1, further comprising forming each piezoelectric ceramic layer in a range from 1 to 25  $\mu$ m in thickness.

19. (New) The method of manufacturing according to claim 1, further comprising applying a voltage between electrodes to obtain variations in a d constant within  $\pm 10\%$  across the surface.

20. (New) A piezoelectric element, comprising:  
a piezoelectric ceramic layer; and  
electrodes provided on both sides of the piezoelectric layer,  
wherein the electrodes include a silver-palladium alloy containing 71 to 99.9% by volume of silver and 0.1 to 29% by volume of palladium.